



Computer Vision and Pattern Recognition Based on Deep Learning

Guest Editor:

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Deadline for manuscript
submissions:

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Message from the Guest Editor

This Special Issue is devoted to the computer vision and pattern recognition methods based on deep learning (CVPR-DL).

In recent years, with the benefits gained from deep learning, great achievements on computer vision and pattern recognition tasks have been made. Nowadays, the solutions of computer vision and pattern recognitions tasks, such as intelligent communication control and management, human face and figureprint recognition, autonomous driving, multimedia communication and smart phones, are becoming integral to people's daily life and more and more popular.

Therefore, in this Special Issue, we invite submissions exploring deep learning research and recent advances in the fields of computer vision and pattern recognition. Both theoretical and experimental studies are welcome, as well as comprehensive review and survey papers.

Keywords:

- object detection
- segmentation
- saliency analysis
- image processing
- computer vision
- audio processing
- image coding
- video compression
- point cloud analysis
- light field processing
- etc





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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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